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PATENT

IN THE UNITED STATES PATENT  
AND TRADEMARK OFFICE

Applicant: Androula G. Nassiopoulou )

Serial No.: 10/502,465 )

Filed: January 16, 2003 )


For: LOW POWER SILICON  
THERMAL SENSORS AND  
MICROFLUIDIC DEVICES BASED  
ON THE USE OF POROUS SEALED  
AIR CAVITY TECHNOLOGY OR  
MICROCHANNEL TECHNOLOGY )

Group Art Unit: To be assigned )

Examiner: To be assigned )

I hereby certify that this paper is being  
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October 21, 2004

  
James P. Zeller  
Reg. No. 28,491

INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents  
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Sir:

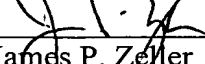
Submitted herewith for consideration by the examiner are copies of the documents  
identified on the attached Form PTO-1449.

Entry and consideration of the submitted documents are solicited.

Respectfully submitted,

MARSHALL, GERSTEIN & BORUN LLP

October 21, 2004

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	30848/40323	10/502,465
	Applicant	
	Androula G. Nassiopoulou	
Filing Date		Group
1/16/03		

## INFORMATION DISCLOSURE STATEMENT

## U.S. PATENT DOCUMENTS

*Examiner Initials	Document Number	Issue Date	Name	Class	Subclass	Filing Date if Appropriate
	6,359,276 B1	03/19/02	Tu	250	338.1	07/06/99

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*Examiner Initials	Document Number	Publication Date	Country	Class	Subclass	Translation	
						Yes	No
	1,251,945	05/03/00	China			Abstract only	
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	"Multi-Walled Microchannels: Free-Standing Porous Silicon Membranes for Use in $\mu$ TAS", Tjerkstra et al., Journal of Microelectromechanical Systems, Vol. 9, No. 4, December 2000, pp. 495-501
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Examiner	Date Considered
*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	